OPERATING INSTRUCTIONS:
DENTON DESK II COLD SPUTTER UNIT
(August 1996 — v1.2)


2. Load specimens into chamber, close lid

3. Turn main power ON (right side), and pump down to less than 30 millitorr

4. Open Argon Tank valve (Do not adjust regulator, chrome valve!)

5. Push SPUTTER button once (this will briefly purge the chamber with argon)

6. Push SPUTTER button a second time, and allow pressure to stabilize at 50 mT

8. Set desired coating time [ 90 seconds – 20 nm ]

9. Push TIMED START, sputtering will start and count down to zero.

10. Adjust CURRENT to 45 mA

11. At completion, reduce current setting to zero (Fully CCW)

12. Turn main power OFF, chamber will vent automatically

13. Turn off Argon gas cylinder!

14. Open chamber lid and remove specimens

15. Close chamber lid.
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